



Design Rules, Technology File, DRC / LVS

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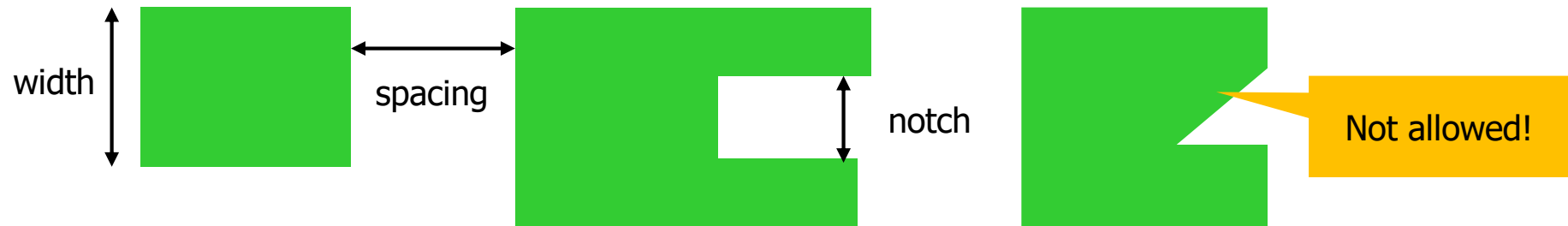


DESIGN RULES

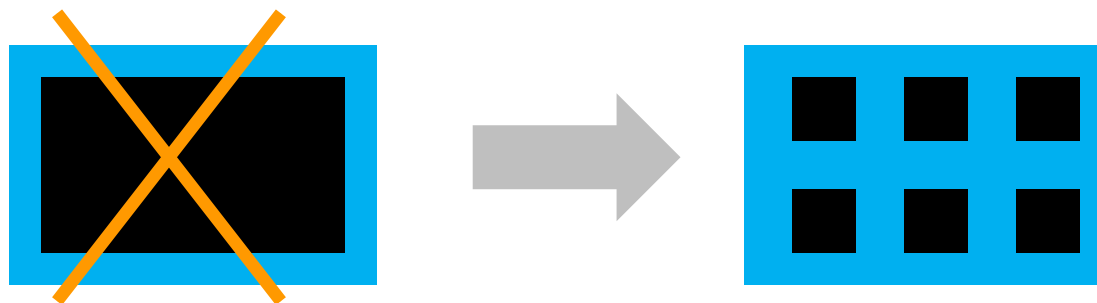


Rules in one Layer

- Caused by manufacturing limits (lithography, etching,..)
- Rules: *Spacing*, *Width*, *Notch* (= 'Kerbe') between same net
 - Finest structure is Poly-silicon for gates



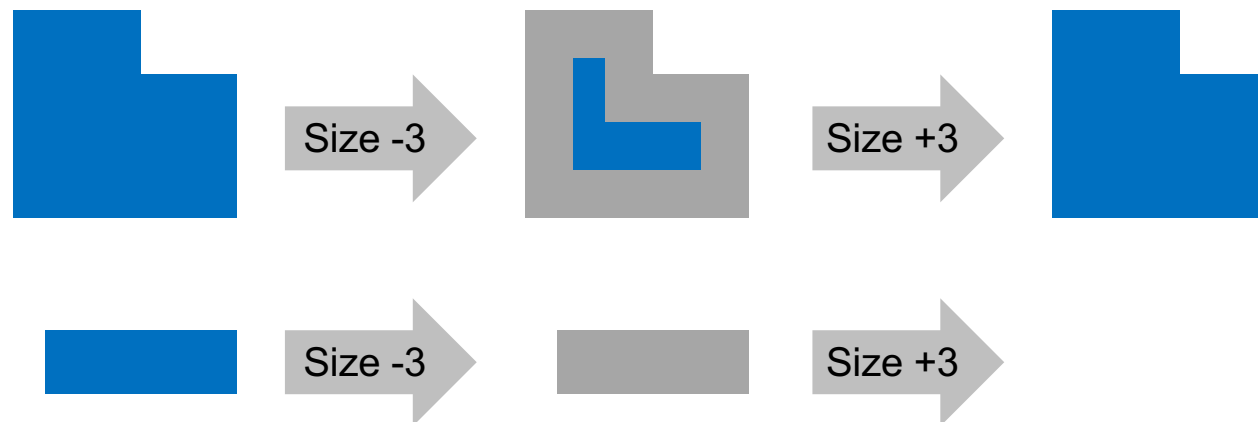
- Some structures have '=' rules, i.e. must have *exactly* a fixed size. Prominent example: contacts and vias
- Larger structures must be created by repetition ('mosaic'):





Rules in one Layer: Wide Structures

- Spacing rules often apply for 'large' = wide structures
- For instance
 - gate spacing for gates $> L_{\min}$ is different (larger)
 - Metal spacing for metal wider W_{\min} can be different
 - Via overlap can be more for wide metal
- How to find wide metal?
 - Can use 'geomSize' function which expands / shrinks shape



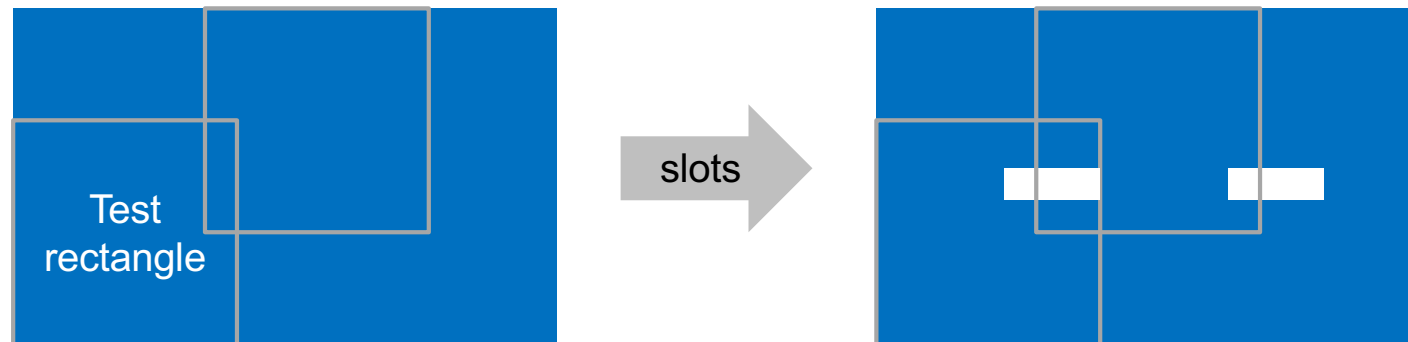
- Shapes < 6 units disappear (after shrink / expand)



Rules in one Layer: Slots

- There are also Maximum rules:
 - Manufacturing of large continuous regions can lead to stress / cracks
 - Definition of size limitation (for instance):
'no square of $10 \times 10 \mu\text{m}^2$ may fit on the metal'

- 'wide metal' must be 'slotted' (holes)
 - This can be by chopping out metal or
 - By adding shapes on a 'metal-slot' layer. These can be copied!
Objects on that layer will later be subtracted.

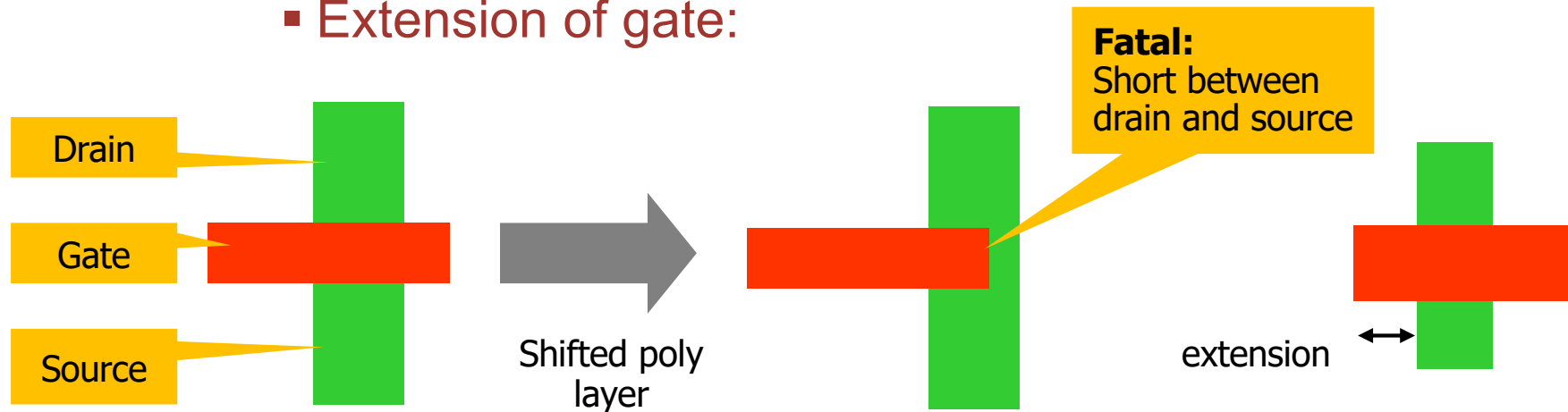


- Slots should not cut current flow →

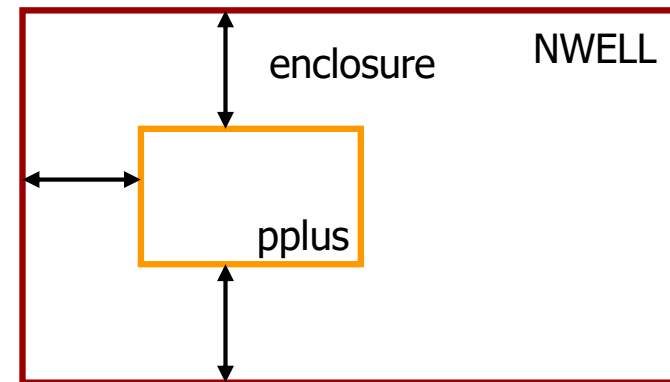


Rules between Layers

- Caused by alignment precision of different masks
- Extension of gate:



- Enclosure / Overlap
 - 'NWELL enclosure of pplus':

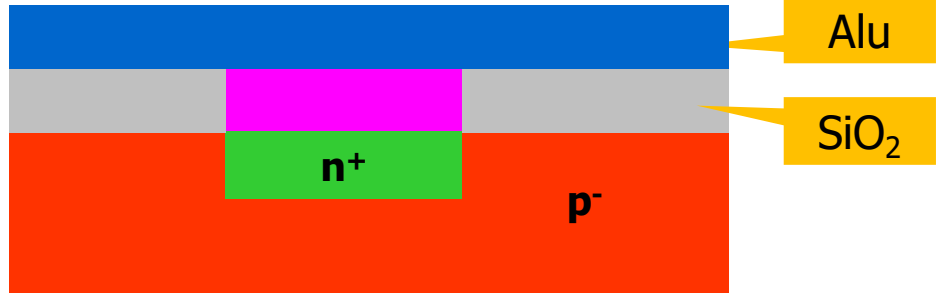




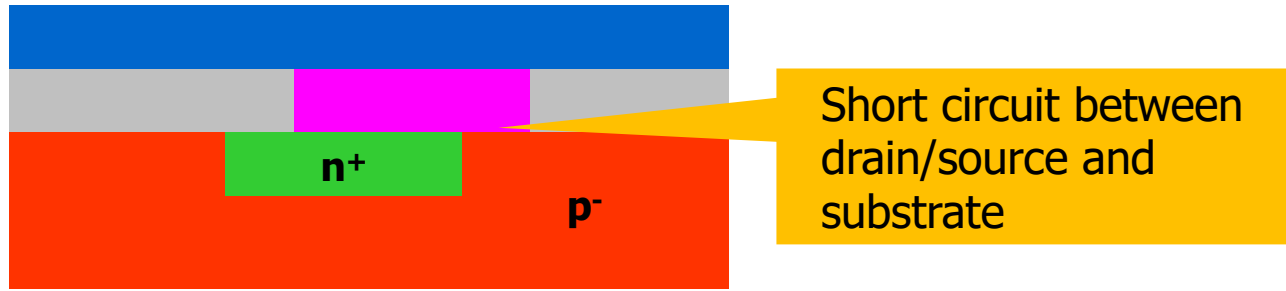
Overlap Required on Drain/Source-Diodes

- Consider contacts of Drain / Source (NMOS)

Ideal
(minimal n⁺ size)



Misaligned
contact mask:



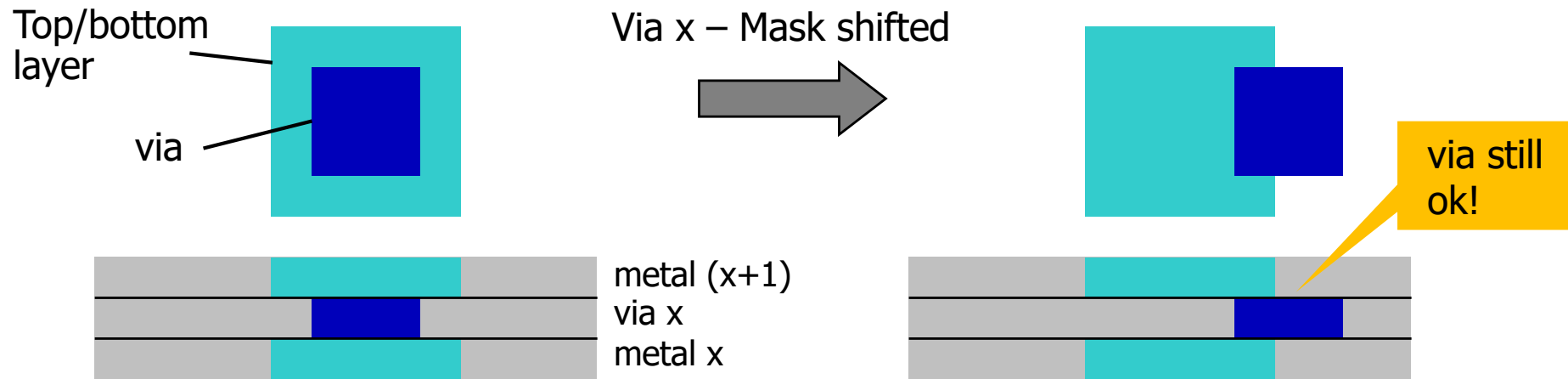
- Solution: Contact hole must be smaller than 'active':





Shifted Vias

- The via/contact can – in principle – be shifted and there is still contact

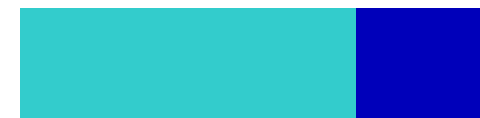


- Therefore, rules for contacts can be aggressive & complicated

- ‘metal must extend via on at least 2 opposite sides’

- This is often allowed:

This not:



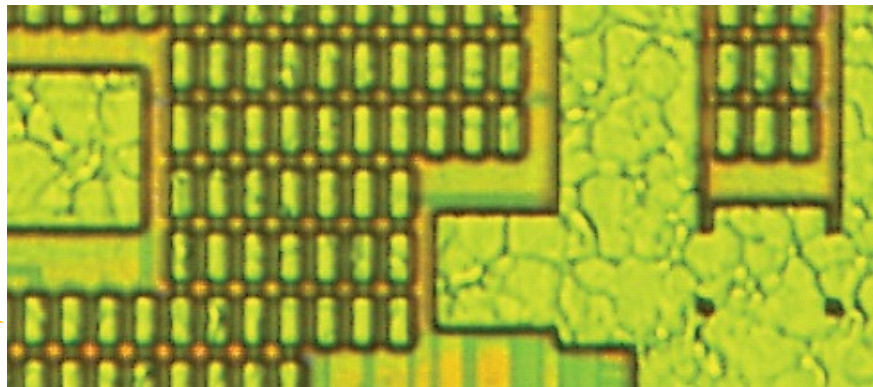


Special Stuff: Area Fill

- The total covered area on most layers must be within certain limit (e.g. $0.3 < f < 0.8$)
 - This guarantees homogeneous production
- This rule can be global or local, i.e. it must be fulfilled in each area $100 \times 100 \mu\text{m}^2$, shifted by $50 \mu\text{m}$ in x/y.
- If the design has too few structures (nearly always!), extra 'dummy' structures must be filled in
- This can be done by scripts by the user or by the fab.
 - To avoid filling (photo diode), there are 'no-fill' layers

Top metal

Fill pattern



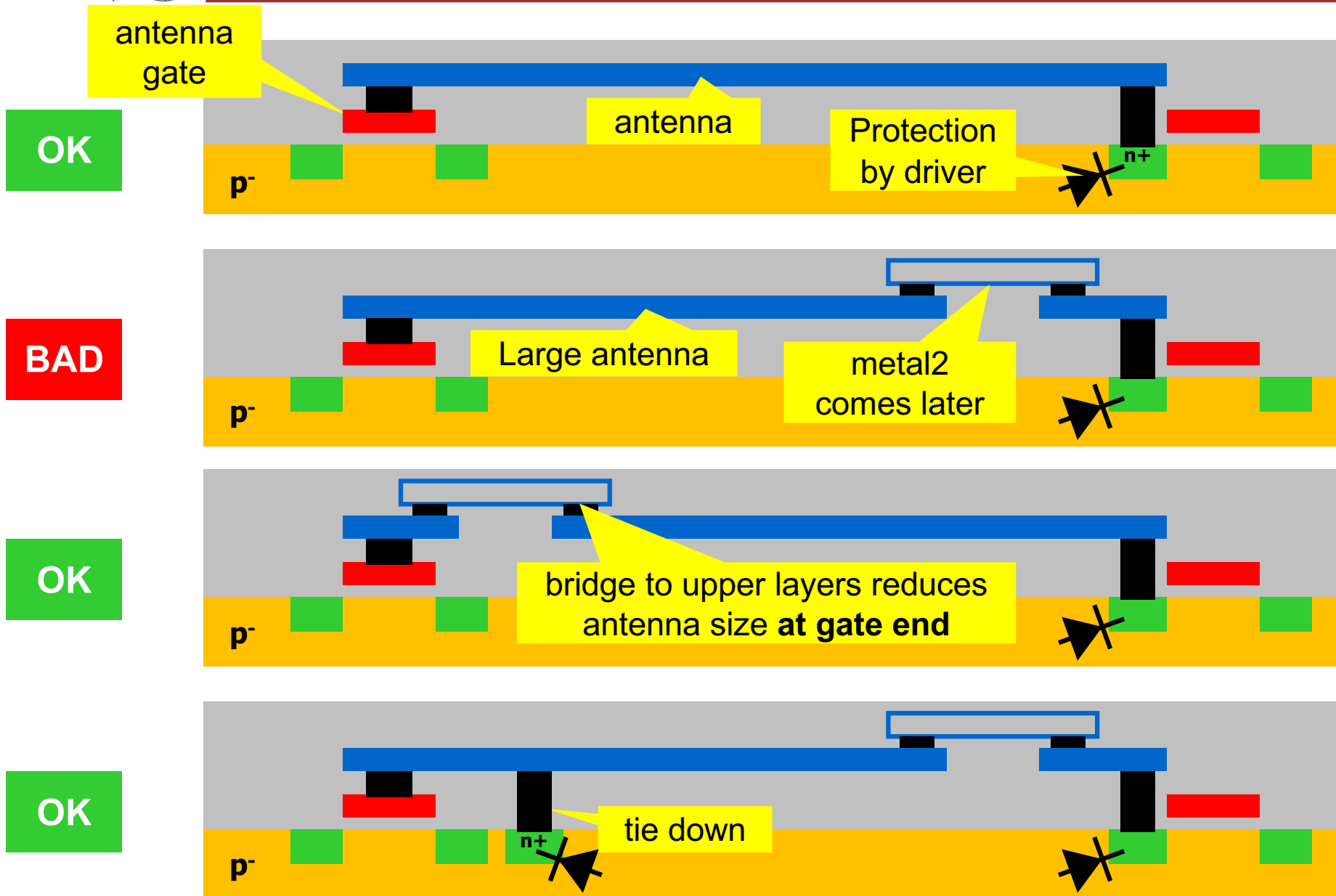


Special Stuff: Antenna

- Some process steps can deposit static charge on structures
 - Amount of charge can depend on *area* or on *periphery*
- The charge Q leads to a voltage $U = Q/C$ which can destroy transistor gates
 - Most dangerous for *large structure* (large Q) and *small gate* (small C)
- The ratio is calculated for each gate. If it exceeds a value, there is danger for an *antenna error*.
- Antenna errors are eliminated if
 - A drain of a MOS is connected directly. The drain diode has enough leakage to discharge the gate. Often, the 'driver' is connected through higher metals and is not 'seen' in the early process steps
 - An explicit 'tie-down' diode is added (n^+ in p-substrate)
 - Signals are fed through higher metals, so that the driving gate is seen when the metal connects (see next page)



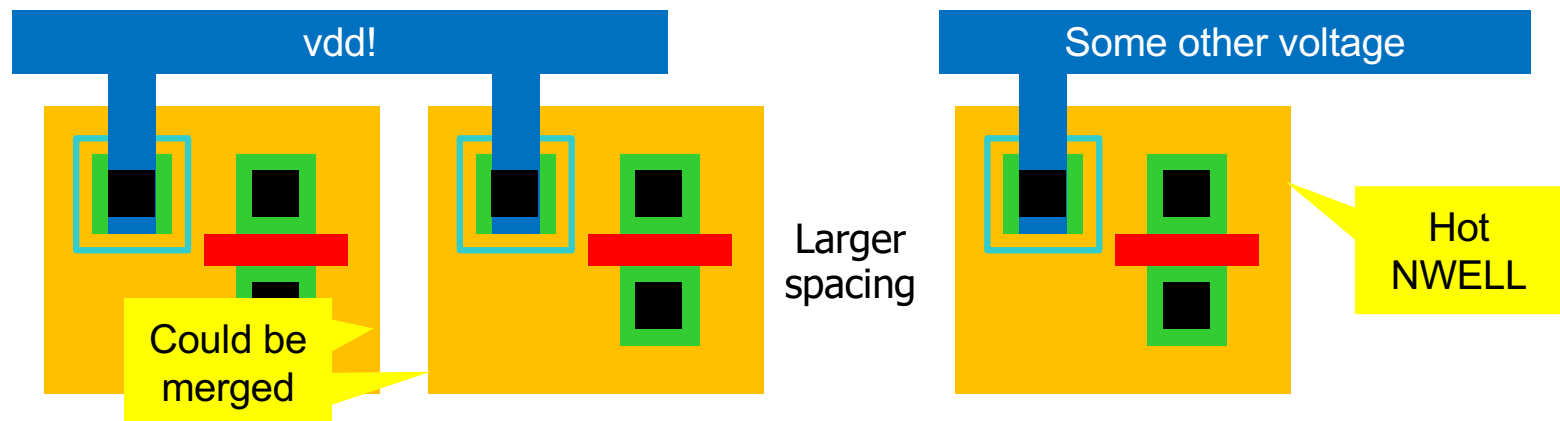
Special Stuff: Antenna (example for NMOS)





Special Stuff: Hot Wells

- Most NWELLS are connected to positive supply.
 - Shorts between such wells are no problem
 - Best merge wells in layout
- Sometimes NWELLS are on different potential (analogue design, Source follower)
 - These wells may not be merged → larger distance required
- Such wells are called ‘hot wells’.
- There are sometimes symbolic layers to tell the tool explicitly that a well is hot and that more severe rules must be applied.





ERC = 'Electrical Rule Check'

■ ERC Examples:

- Floating Metal, Poly,...
- Antenna rules
- Shorted Drain & Source of a MOS
- No substrate- or well contact ('figure having no stamped connection')
- Different contacts of substrate / well are connected to different nets ('Figure having multiple stamped connections')
(No automatic connection of these nets to avoid circuit parts which are only connected via substrate – can be fatal!)
- Distance of MOS to next substrate / well contact too large
(Latchup rule)

■ Difference between DRC und ERC is soft

- DRC must sometimes ,understand‘ the circuit



TECHNOLOGY FILE



Technology File

- The technology file is provided by the technology vendor
- It adapts the CAD tool:
 - Define colours, layers, ...
 - Create menus and commands (e.g. create contact)
 - Define widths, spacings,...
 - Provide parameterized cells (PCELLs) for MOS, Caps, ...
- It contains (maybe in separate files)
 - DRC rules
 - ERC rules
 - Extraction rules
 - LVS rules (e.g. permutation of devices)
- → Example file in a 0.8 μ m technology



LVS LAYOUT VERSUS SCHEMATIC



What LVS does

■ 3 Steps:

1. Extract the *schematic* netlist

- travel down the hierarchy until a view is in the 'stop' list.
- for instance, we can 'keep' an inverter as a cell, not resolve it into MOS!
- ignore symbols for instance in analogLib

2. Extract the *layout* netlist

3. *Compare* the two netlists

- Devices and nets without labels often have *different* names!
- Difficult task!
- Naively, require 1:1 match
- In reality, allow certain topological differences
 - the order of serial connected resistors does not matter
 - two serial resistors are equivalent to one with sum resistivity
 - ...





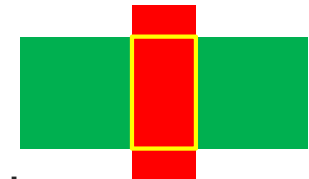
Layout Extraction

- The extraction must

1. Find the devices
2. Get (geometric) parameters of the devices

For instance, for a MOS:

- W, L
- AD, PD, AS, PS
- ...



gate = poly AND active

- The way this is done influences the result in special cases:

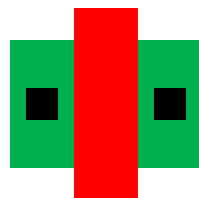
```
w = measureParameter( length ( gate coincident poly ) 0.5e-6 )
```

```
a = measureParameter( area ( gate ) 1.0e-12 )
```

```
l = calculateParameter( a / w )
```

Convert cadence
Units to μm or μm^2

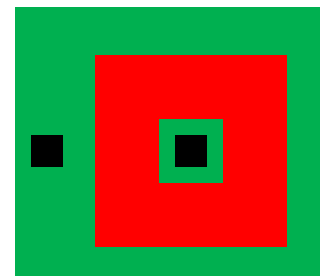
gives correct result for rectangular MOS, but no good value for enclosed MOS:



$$w = 4 \times 0.5 = 2$$

$$a = 2$$

$$l = 2/2 = 1$$



$$w = 16 \times 0.5 = 8$$

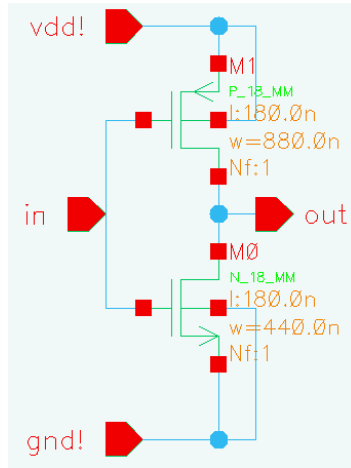
$$a = 8$$

$$l = 8/8 = 1$$



Example for 1:1 match

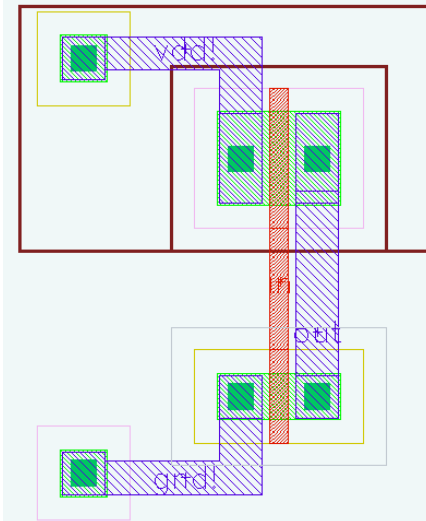
Schematic



Extracted schematic netlist:

```
* 2 instances
i M1 P_18_MM out in vdd! vdd!
L 1.8e-07 M 1 W 8.8e-07
i M0 N_18_MM out in gnd! gnd!
L 1.8e-07 M 1 W 4.4e-07
```

Layout



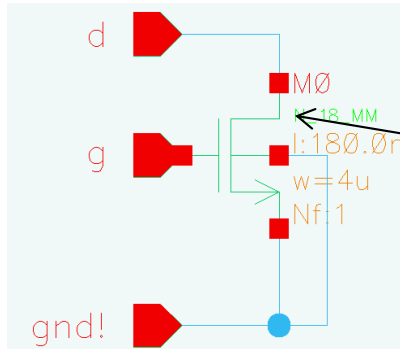
Extracted layout netlist:

```
* 2 instances
i av1 N_18_MM out in gnd! gnd!
l 1.8e-07 w 4.4e-07;
i av2 P_18_MM out in vdd! vdd!
l 1.8e-07 w 8.8e-07;
```



Single MOS in schematic ↔ multiple MOS in layout

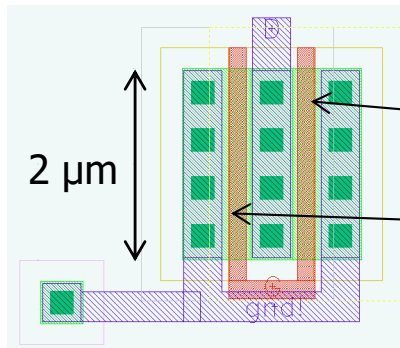
Schematic



Extracted schematic netlist:

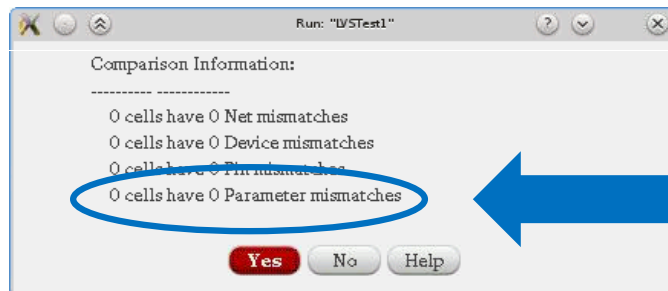
```
* 1 instances
i M0 N_18_MM d g gnd! gnd!
L 1.8e-07 M 1 W 4e-06
```

Layout



Extracted layout netlist:

```
* 2 instances
i m0 N_18_MM gnd! G D gnd!
1 1.8e-07 w 2e-06
i m1 N_18_MM D G gnd! gnd!
1 1.8e-07 w 2e-06 ;
```



MATCH!
But why?

Comparison finds parallel MOS (with same L) and calculates W as W * m



LVS: What permutations,... are allowed ?

- Are two serial MOS with same W (W/L_1 , W/L_2) equivalent to a single MOS with $L = L_1 + L_2$?
- Is it ok to swap order of serial MOS?
 - This is required to simplify LVS of CMOS gates (the two inputs are logically equivalent, but topologically different)
 - This is dangerous in tri-state logic, dynamic logic,...
- How much tolerance is allowed in W, L, R, \dots ?
- Should serial caps be replaced by $1/C_{\text{sum}} = 1/C_1 + 1/C_2$?

- These subtle things are defined in the 'Compare' rules!